

Form PTO-1449		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE			ATTY. DOCKET NO. MI22-1568		SERIAL NO. 09/879,335	
LIST OF ART CITED BY APPLICANT (Use several sheets if necessary)					APPLICANT Vishnu K. Agarwal et al		FILING DATE June 11, 2001	
					GROUP 2813			
*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate	
							Yes	No
<i>CAT</i> <i>CAT</i> <i>CAT</i>		AA 5,869,382	02-1999	Kabota				
		AB 5,940,676	08-1999	Fazan et al				
		AC 5,714,402	02-1998	Choi				
		AD						
		AE						
		AF						
		AG						
		AH						
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		AL						
	FOREIGN PATENT DOCUMENTS							
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EXAMINER				DATE CONSIDERED				
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ATTY. DOCKET NO.
M122-1568

SERIAL NO.
Unknown

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APPLICANT
Vishnu K. Agarwal et al

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U.S. PATENT DOCUMENTS

*Examiner Initial	Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
MA	AA 6,232,168	5/15/2001	Coursey			
	AB					
	AC					
	AD					
	AE					
	AF					
	AG					
	AH					
	AI					
	AJ					
	AK					
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FOREIGN PATENT DOCUMENTS

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U.S. DEPARTMENT OF COMMERCE
PATENT AND TRADEMARK OFFICE

ATTY. DOCKET NO.
M122-1568

SERIAL NO.
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LIST OF ART CITED BY APPLICANT
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APPLICANT Vishnu K. Agarwal, et al.

FILING DATE June 11, 2001

GROUP 2813

U.S. PATENT DOCUMENTS

*Examiner Initial	Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
YB	AA 5.786.248	07/1998	Schuegraf			
	AB 3.571.914	03/1971	Lands, et al.			
	AC 4.464.701	08/1984	Roberts et al.			
	AD 5.504.041	04/1996	Summerfelt			
	AE 5.471.364	11/1995	Summerfelt et. al.			
	AF 5.654.222	08/1997	Sandhu et. al.			
	AG 5.663.088	09/1997	Sandhu et. al.			
	AH 5.442.213	08/1995	Okudaira			
	AI 5.910.880	06/1999	DeBoer et. al.			
	AJ 5.843.830	12/1998	Gractinger et. al.			
	AK 5.854.107	12/1998	Park et al.			
YB	AL 5.622.883	04/1997	Kim			

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FOREIGN PATENT DOCUMENTS

	Document Number	Date	Country	Class	Subclass	Translation	
						Yes	No
YB	AM 7611928	3/77	Netherlands				X
	AN						

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OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)

YB	AO	Kamiyama, Satoshi et al., "Ultrathin Tantalum Oxide Capacitor Dielectric Layers Fabricated Using Rapid Thermal Nitridation Prior to Low Pressure Chemical Vapor Deposition: J. Electrochem. Soc., Vol. 140, #6, pp 1618-25 (6/1993)
	AP	Yoshimaru, M., et al., "High Quality Ultra Thin SiO ₂ N ₂ Film Selectively Deposited on Poly-Si Electrode by LPCVD with <i>In Situ</i> HF Vapor Cleaning". <i>IEEE</i> , pp. 271-274 (04/1992)
	AO	Kamiyama, S., et al., Highly Reliable 2.5 nm Ta ₂ O ₅ Capacitor Process Technology for 256 Mbit DRAMs". <i>IEEE</i> , pp. 827-830 (9/1991)
YB	AR	Eimori, T., et al., "A Newly Designed Planar Stacked Capacitor Cell with high Dielectric Constant Film for 256Mbit DRAM". 1993 <i>IEEE</i> , pp. 631-634.

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EXAMINER *YB* DATE CONSIDERED *3/18/02*

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		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE			ATTY. DOCKET NO. M12-1568	SERIAL NO. 09/879,333	
		LIST OF ART CITED BY APPLICANT (Use several sheets if necessary)					APPLICANT Kunal R. Parekh, et al.
		FILING DATE June 11, 2001			GROUP 2813		
U.S. PATENT DOCUMENTS							
*Examiner Initial	Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate	
AA	5,597,756 /	01/1997	Fazan et al.				
AB	5,843,818 /	12/1998	Joo et al.				
AC	5,866,453 /	02/1999	Prall et al.				
AD	5,488,011 /	01/1996	Fiura et al.				
AE	5,405,796 /	04/1995	Jones				
AF	5,346,844 /	09/1994	Cho				
AG	5,352,623 /	10/1994	Kamiyama				
AH	5,438,012 /	08/1995	Kamiyama				
AI	5,893,980 /	04/1999	Cho				
AJ							
AK							
AL							
FOREIGN PATENT DOCUMENTS							
	Document Number	Date	Country	Class	Subclass	Translation	
						Yes	No
AM							
AN							
OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)							
AO			Fazan, P.C., et. al., "A High-C Capacitor (20.4fF/ μm^2) with Ultrathin CVD-Ta ₂ O ₅ Films Deposited on Rugged Poly-Si for High Density DRAMs", 1992 IEEE, pp. 263-266.				
AP			Lescheherre, P-Y, et. al., "A Gbit-Scale DRAM Stacked Capacitor Technology with ECR MOCVD SrTiO ₃ and RIE Patterned RuO ₄ /TiN Storage Nodes", 1994 IEEE, pp. 831-834.				
AQ			Yamaguchi, H., et. al., "Structural and Electrical Characterization of SrTiO ₃ Thin Films Prepared by Metal Organic Chemical Vapor Deposition", Jpn. J. Appl. Phys. Vol. 32 (1993), Pt. 1, No. 9B, pp. 4069-4073.				
AR							
EXAMINER			DATE CONSIDERED				
yjn			8/8/02				
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LIST OF ART CITED BY APPLICANT (Use several sheets if necessary)					APPLICANT Victor K. Agnew et al			
					FILING DATE June 11, 2001		GROUP 213	
U.S. PATENT DOCUMENTS								
*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate	
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	AB							
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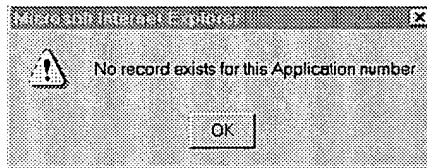
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